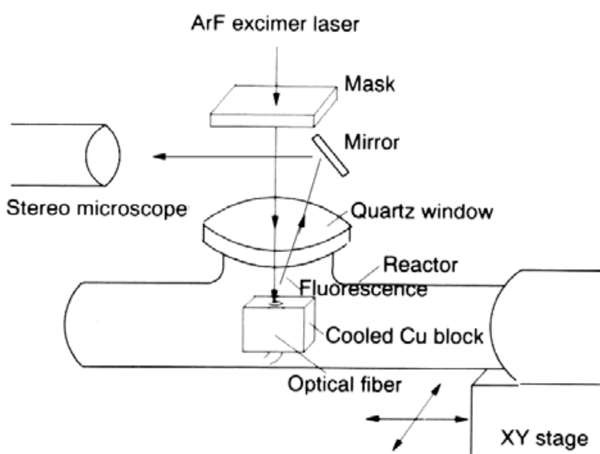
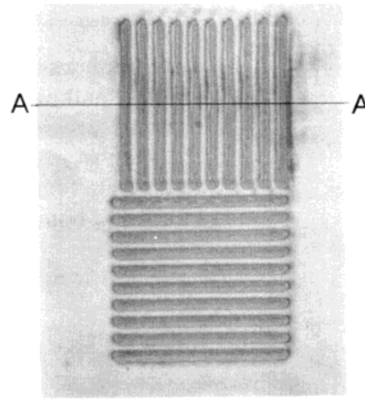
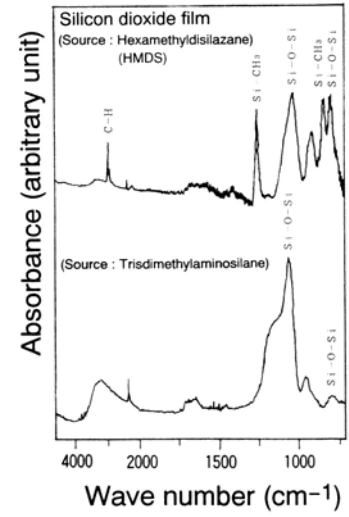
Laser Processes and Stealth Dicing

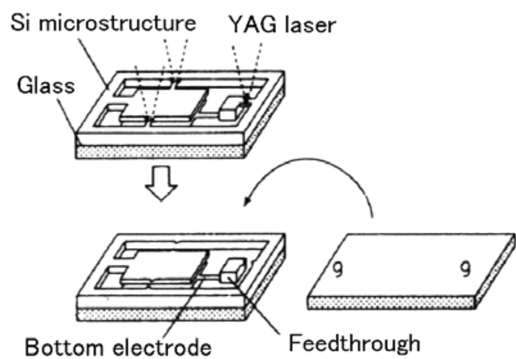


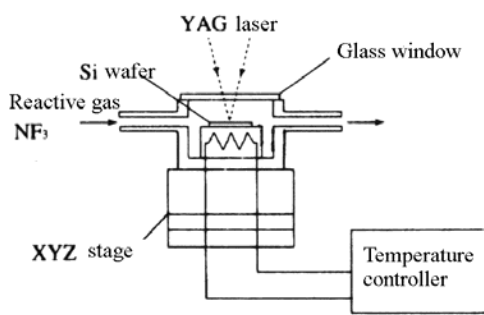


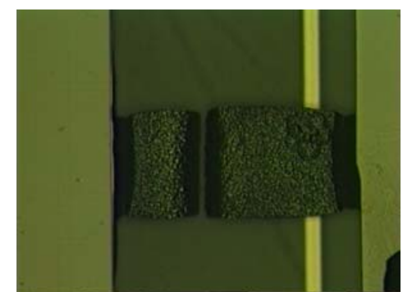


Laser projection CVD

Reference : K.Takashima, K.Minami, M.Esashi and J.Nishizawa, Laser Projection CVD Using the Low Temperature Condensation Method, Applied Surface Science, 79/80 (1994) pp.366-374

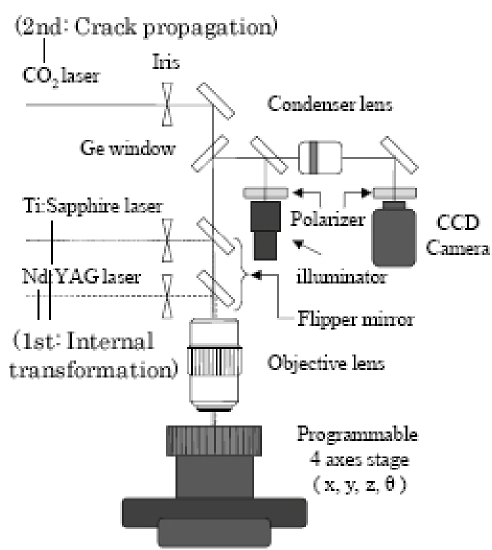


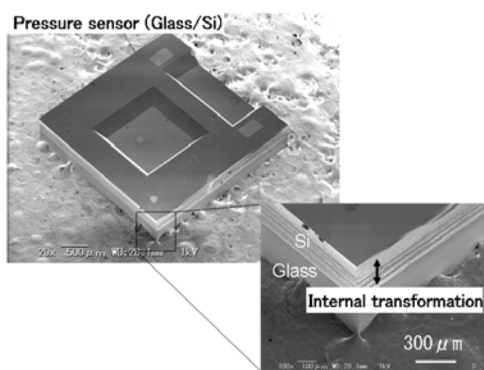


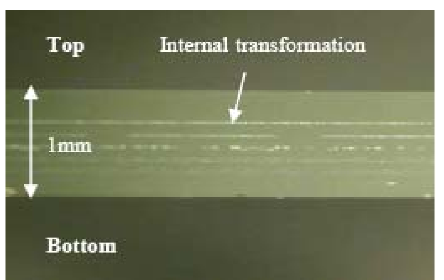


Laser assisted Si etching

参考文献 : K.Minami, Y.Wakabayashi, M.Yoshida, K.Watanabe and M.Esashi, YAG Laser-Assisted Etching of Silicon for Fabricating Sensors and Actuators, J. of Micromechanics and Microengineering, 3 (1993) pp.81-86







Laser (stealth) dicing of Si-glass structure (Tohoku Univ. - Inst. For Laser Tech.)

Reference : M.Fujita, Y.Izawa, Y.Tsurumi, S.Tanaka, H.Fukushi, K.Sueda, Y.Nakata, M.Esashi and N.Miyanaga , Debris-free Low-stress High-speed Laser Assisted Dicing for Multi-layered MEMS, Trans. IEE of Japan, 130-E (2010) pp.118-123